

Fig. 5D

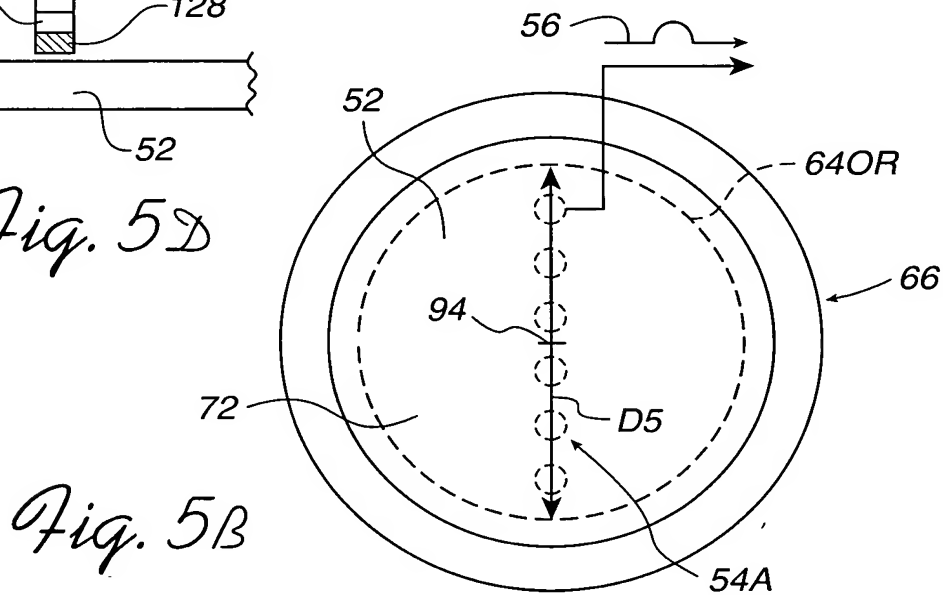
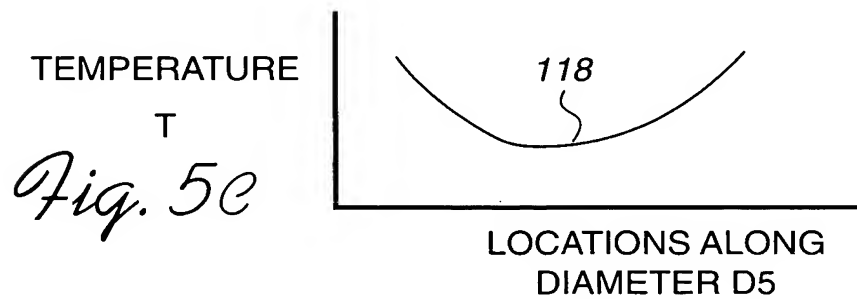


Fig. 5B



Title: APPARATUS METHODS FOR CONTROLLING WAFER TEMPERATURE IN
CHEMICAL MECHANICAL POLISHING

Inventor: Nicoias Bright Application No, 10/722,839 Docket: LAM2P318D

Sheet 7 of 9 Replacement Sheet

